

Title (en)
MICROELECTROMECHANICAL SYSTEM AND METHOD FOR MANUFACTURING THE SAME

Title (de)
MEMS UND METHODE ZUR HERSTELLUNG DES MEMS

Title (fr)
MEMS ET MÉTHODE DE SA PRODUCTION

Publication
EP 3227898 A1 20171011 (EN)

Application
EP 14808601 A 20141204

Priority
EP 2014076609 W 20141204

Abstract (en)
[origin: WO2016086997A1] A MEMS comprises a stack comprising a first layer and a second layer having sides facing each other. The first layer and the second layer are attached to each other by a contact material at opposing contact regions of the sides of the first and the second layer. The contact material forms a distance between the sides of the first and the second layer. A first signal line is arranged at the side of the first layer. A second signal line is arranged at the side of the second layer. The first signal line, at a first longitudinal portion of the first signal line, laterally extends through the contact region of the first side of the first layer. The second signal line comprises a void in a void region at a location in the corresponding contact region of the side of the second layer and opposing the first signal line, The first signal line, at a second longitudinal portion of the first signal line, faces the second signal line spaced apart from the second signal line.

IPC 8 full level
H01H 1/00 (2006.01); **H01H 59/00** (2006.01); **H01P 1/12** (2006.01); **H01P 3/02** (2006.01); **H01P 3/08** (2006.01)

CPC (source: EP)
H01H 59/0009 (2013.01); **H01P 1/127** (2013.01); **H01H 2001/0078** (2013.01)

Citation (search report)
See references of WO 2016086997A1

Designated contracting state (EPC)
AL AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO RS SE SI SK SM TR

Designated extension state (EPC)
BA ME

DOCDB simple family (publication)
WO 2016086997 A1 20160609; EP 3227898 A1 20171011; EP 3227898 B1 20181121

DOCDB simple family (application)
EP 2014076609 W 20141204; EP 14808601 A 20141204